ROBOT FOR HANDLING WAFER CASSETTE

Patent number:

JP5146984

Publication date:

1993-06-15

Inventor:

SHIAKU HOTSU

Applicant:

MURATA MACH LTD

Classification:

- international:

B25J15/08; B25J9/06; H01L21/68

- european:

Application number:

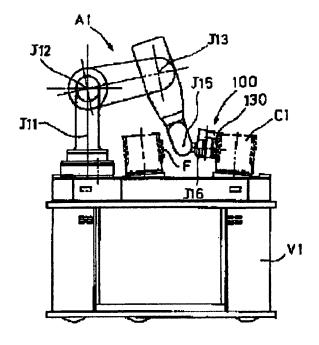
JP19910192784 19910708

Priority number(s):

Abstract of JP5146984

PURPOSE:To hold adjacent wafer cassettes having flanges on side face sides in succession with a simple action.

CONSTITUTION:In a wafer cassette handling robot having a hand 100 fitted rotatably by a rotary shaft J16 at the tip of an arm A1 provided with multiple joints and a pair of chuck sections 130 provided on the hand 100 to hold a semiconductor wafer cassette C1, a pair of chuck sections 130 are arranged point-symmetrically with the rotary shaft J16 as viewed from the axial direction of the rotary shaft 16.



Data supplied from the esp@cenet database - Patent Abstracts of Japan